

Abstract of the Disclosure

A method of manufacturing a stamper/imprinter for use in patterning of a recording medium, comprises sequential steps of:

- (a) providing a substrate/workpiece comprising:
 - 5 (i) a topographical pattern formed in a portion of a surface of the substrate/workpiece, the pattern defining a periphery; and
 - (ii) an alignment mark formed in another portion of the surface of surrounding the periphery;
- (b) forming an opaque protective film overlying the entirety of the
10 surface;
- (c) removing a peripheral portion of the protective film to expose the alignment mark;
- (d) removing selected portions of the substrate/workpiece while utilizing the alignment mark for accurate alignment during the removal process;
15 and
- (e) removing remaining portions of the protective film prior to use.